

A Time-Dependent Study of Radio-Frequency Plasma Sheaths Using the Flux-Corrected Transport (FCT) Algorithm

Plasma sheaths are non-neutral boundary layers that form adjacent to material surfaces due to the higher mobility of electrons relative to ions, establishing a strong electrostatic field normal to the boundary. Under steady-state (DC) conditions, sheath formation is governed by the Bohm criterion, which requires ions to enter the sheath with a velocity exceeding a critical value [1–3]. This time-independent limit provides a fundamental benchmark for more general time-dependent sheath models.

In many practical plasma applications, electrodes are often driven by radio-frequency (RF) sources, introducing explicit time dependence into the sheath dynamics through oscillatory boundary conditions. In RF-driven sheaths, the sheath potential $\phi_s(t)$, sheath width $d_s(t)$, and electric field $E(x,t)$, vary periodically in time, leading to modulation of ion acceleration and energy deposition at the boundary. The characteristic ion response depends on the ratio of the RF frequency ω to the ion plasma frequency ω_{pi} . For $\omega \ll \omega_{pi}$ ions respond quasi-statically to the instantaneous sheath electric field, whereas for $\omega \sim \omega_{pi}$, ion motion becomes significant and a fully time-dependent treatment is required. Many analytical RF sheath models, therefore, rely on simplifying assumptions such as cold ions, negligible ion inertia, or time-averaged electric fields, which restrict their validity in regimes where finite ion temperature and pressure effects play an important role.

Motivated by these limitations, the present work develops a fully time-dependent fluid model for collision-less RF plasma sheaths [4], incorporating ion pressure effects and driven by a sinusoidal current source. The complete set of ion fluid equations is solved numerically using a flux-corrected transport (FCT) algorithm to ensure stability and accuracy. An

equivalent circuit model is coupled self-consistently with the fluid equations to relate the instantaneous sheath potential to the sheath thickness. The present model provides an enhanced and self-consistent description of RF sheath dynamics, particularly in regimes where pressure effects cannot be overlooked

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